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IEEE Electron Device Letters, Volume: 23 Issue: 9, Sept. 2002

Page(s): 505 -507

[\[Abstract\]](#) [\[PDF Full-Text \(219 KB\)\]](#) **JNL****2 Plasma impedance in a narrow gap capacitively coupled RF discharge**
*Bera, K.; Chen-An Chen; Vitello, P.*Plasma Science, IEEE Transactions on, Volume: 30 Issue: 1 Part: 1, Feb. 2002
Page(s): 144 -145[\[Abstract\]](#) [\[PDF Full-Text \(189 KB\)\]](#) **JNL****3 The development of a diamond switch for RF pulse compression system**
*Xiaoxi Xu; Schein, J.; Niansheng Qi; Prasad, R.R.; Krishnan, M.; Fumihiko, T.; Tantawi, S.G.*Plasma Science, IEEE Transactions on, Volume: 29 Issue: 1, Feb 2001
Page(s): 85 -92[\[Abstract\]](#) [\[PDF Full-Text \(184 KB\)\]](#) **JNL****4 Amorphous superlattice structures with carbon as a wide bandgap component***Mazurczyk, R.; Gazicki, M.*

Wide Bandgap Layers, 2001. Abstract Book. 3rd International Conference on Applications of , 2001
Page(s): 128

[\[Abstract\]](#) [\[PDF Full-Text \(44 KB\)\]](#) [CNF](#)

5 Synthesis of cubic boron nitride thin films by microwave PECVD

Thevenin, P.; Soltani, A.; Bath, A.

Wide Bandgap Layers, 2001. Abstract Book. 3rd International Conference on Applications of , 2001
Page(s): 118 -119

[\[Abstract\]](#) [\[PDF Full-Text \(82 KB\)\]](#) [CNF](#)

6 Forming carbon films on cemented carbide surface using RF PCVD

Grabarczyk, J.; Niedzielski, P.; Louda, P.

Wide Bandgap Layers, 2001. Abstract Book. 3rd International Conference on Applications of , 2001
Page(s): 110 -111

[\[Abstract\]](#) [\[PDF Full-Text \(200 KB\)\]](#) [CNF](#)

7 A study of plasma-polymerized aniline films

Tamirisa, P.A.; Pedrow, P.D.; Osman, M.A.; Mahalingam, R.; Liddell, K.C.

Pulsed Power Plasma Science, 2001. IEEE Conference Record - Abstracts , 2001
Page(s): 553

[\[Abstract\]](#) [\[PDF Full-Text \(74 KB\)\]](#) [CNF](#)

8 Characterization of SiC thin films grown on Si by inductively coupled chemical vapor deposition at low temperatures

Tai-Fa Young; Chin-Lien Hsiao; Chia-Lin Peng

Semiconducting and Insulating Materials Conference, 2000. SIMC-XI. Internat. 2000
Page(s): 291 -294

[\[Abstract\]](#) [\[PDF Full-Text \(168 KB\)\]](#) [CNF](#)

9 Effect of passivation on AlGaIn/GaN HEMT device performance

Tilak, V.; Green, B.; Kim, H.; Dimitrov, R.; Smart, J.; Schaff, W.J.; Shealy, J.; Eastman, L.F.

Compound Semiconductors, 2000 IEEE International Symposium on , 2000
Page(s): 357 -363

[\[Abstract\]](#) [\[PDF Full-Text \(272 KB\)\]](#) [CNF](#)

10 Effects of H₂-dilution and plasma power in amorphous silicon deposition: comparison of microstructural evolution and solar cell performance

Ferlauto, A.S.; Rovira, P.I.; Koval, R.J.; Wronski, C.R.; Collins, R.W.
Photovoltaic Specialists Conference, 2000. Conference Record of the Twenty IEEE, 2000
Page(s): 713 -716

[\[Abstract\]](#) [\[PDF Full-Text \(320 KB\)\]](#) [CNF](#)

11 High rate deposition of microcrystalline silicon solar cells using PECVD

Roschek, T.; Repmann, T.; Muller, J.; Rech, B.; Wagner, H.
Photovoltaic Specialists Conference, 2000. Conference Record of the Twenty IEEE, 2000
Page(s): 150 -153

[\[Abstract\]](#) [\[PDF Full-Text \(340 KB\)\]](#) [CNF](#)

12 Development of a diamond RF switch for a pulse compression system

Xiaoxi Xu; Schein, J.; Niansheng Qi; Prasad, R.R.; Krishnan, M.; Tamura, F., S.
Plasma Science, 2000. ICOPS 2000. IEEE Conference Record - Abstracts. The IEEE International Conference on, 2000
Page(s): 125

[\[Abstract\]](#) [\[PDF Full-Text \(92 KB\)\]](#) [CNF](#)

13 1 MW, 140 GHz, CW gyrotron for Wendelstein 7-X

Dammertz, G.; Alberti, S.; Arnold, A.; Borie, E.; Erckmann, V.; Forster, W.; Gantenbein, G.; Garin, P.; Giguet, E.; Illy, S.; Kasperek, W.; Laqua, H.; Le Goff, Y.; Magne, R.; Michel, G.; Muller, G.; Piosczyk, B.; Tran, M.Q.; ... M.
Plasma Science, 2000. ICOPS 2000. IEEE Conference Record - Abstracts. The IEEE International Conference on, 2000
Page(s): 174

[\[Abstract\]](#) [\[PDF Full-Text \(76 KB\)\]](#) [CNF](#)

14 Modeling of a two stage RF plasma reactor for SiC deposition

Petrov, G.M.; Giuliani, J.L.
Plasma Science, 2000. ICOPS 2000. IEEE Conference Record - Abstracts. The IEEE International Conference on, 2000
Page(s): 205

[\[Abstract\]](#) [\[PDF Full-Text \(84 KB\)\]](#) [CNF](#)

15 **Fabrication of amorphous carbon films by using organic hydrocarbons**

Xu, J.; Li, W.; Chen, K.J.; Xu, J.B.

Electron Devices Meeting, 2000. Proceedings. 2000 IEEE Hong Kong , 2000

Page(s): 50 -53

[\[Abstract\]](#) [\[PDF Full-Text \(256 KB\)\]](#) **CNF**

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